

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

OFFICIAL

<p>Applicant(s): Crkvcnac et al.</p> <p>Application No.: 10/734,945</p> <p>Filed: 12/11/2003</p> <p>Title: CHEMICAL MECHANICAL POLISHING METHOD FOR REDUCING SLURRY REFLUX</p> <p>Attorney Docket No.: 03042US</p>	<p>RECEIVED CENTRAL FAX CENTER</p> <p>JUL 22 2004</p> <p>Art Unit:</p> <p>Examiner:</p>
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PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Before examination, please amend this application as follows: